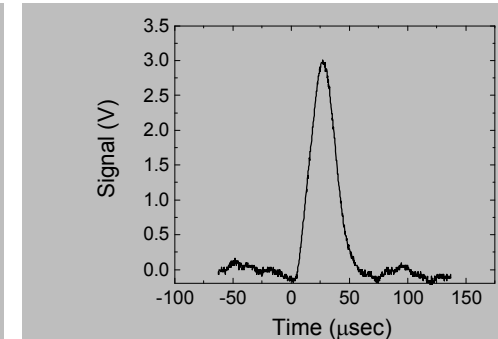
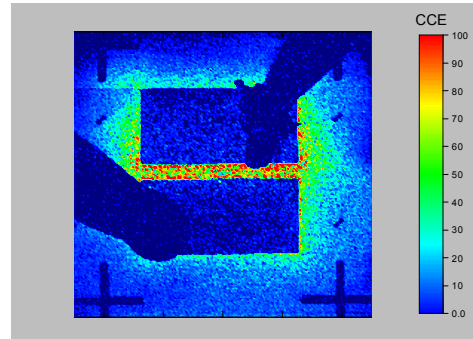


Exceptional service in the national interest

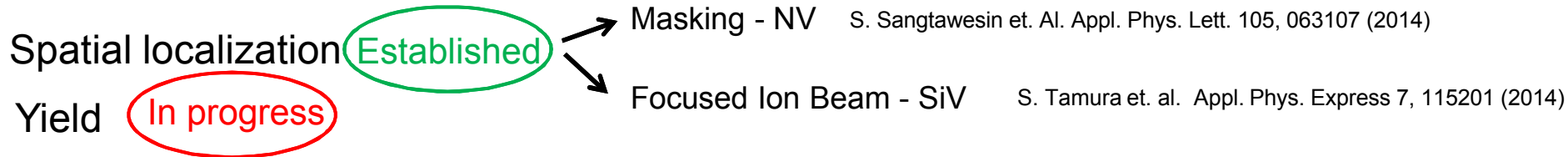


Single ion detection in diamond: A path for deterministic color center creation

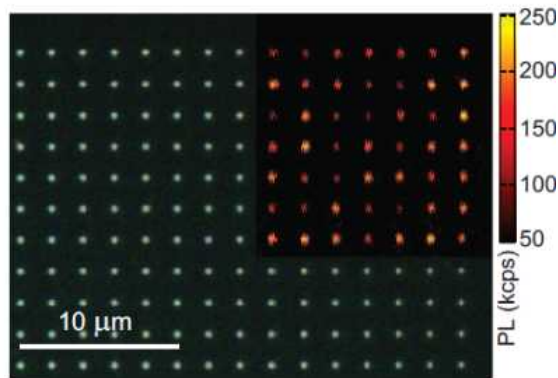


J. Abraham, B. Aguirre, J. Pacheco,
R. Camacho, E. Bielejec

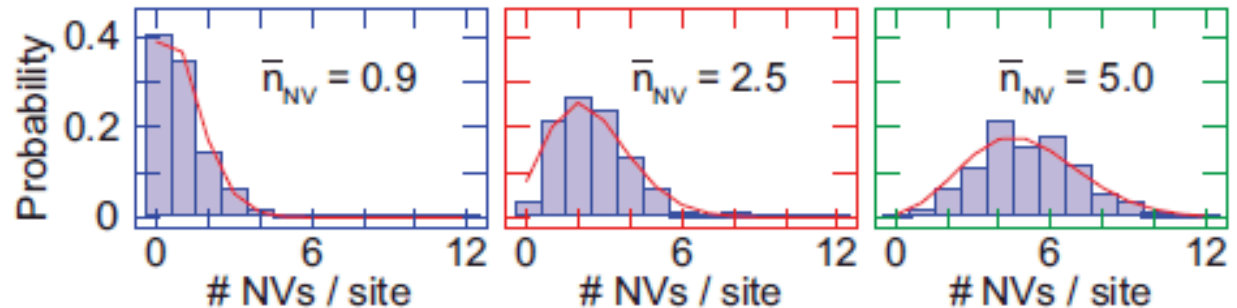
Deterministic Fabrication



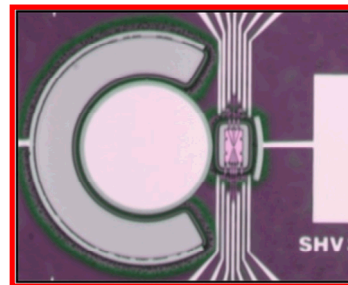
S. Sangtawesin et. al. Appl. Phys. Lett. 105, 063107 (2014)



Poisson Statistics

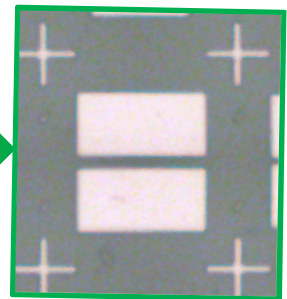


Single Ion Detector in Silicon



J.A. Seamons, et. al. Appl. Phys. Lett, 93, 043124 (2008)
E Bielejec, et. al. Nanotechnology 21, 085201 (2010)

Single Ion Detector in Diamond

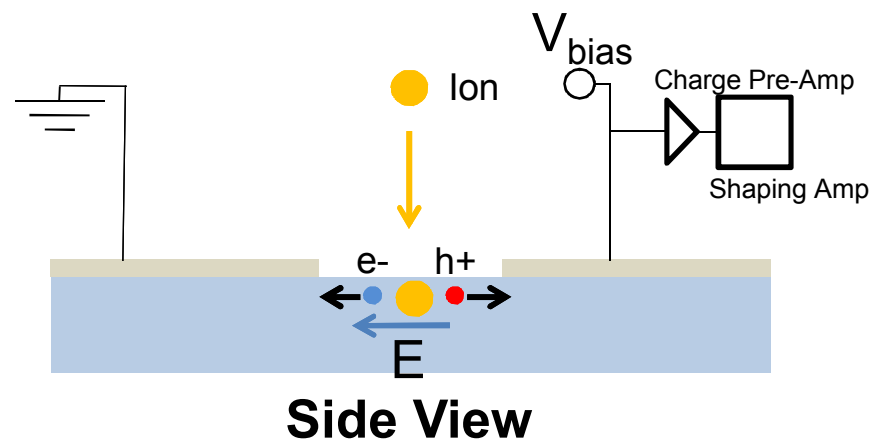


Our work:
Translating single
ion detection to
diamond

In-situ single ion detection is a demonstrated path for yield control

By counting in ions, we will remove a source of Poisson statistics

Physics of Ion Detection



Shockley-Ramo Theorem:

$$i = q\vec{v} \cdot \vec{E}$$

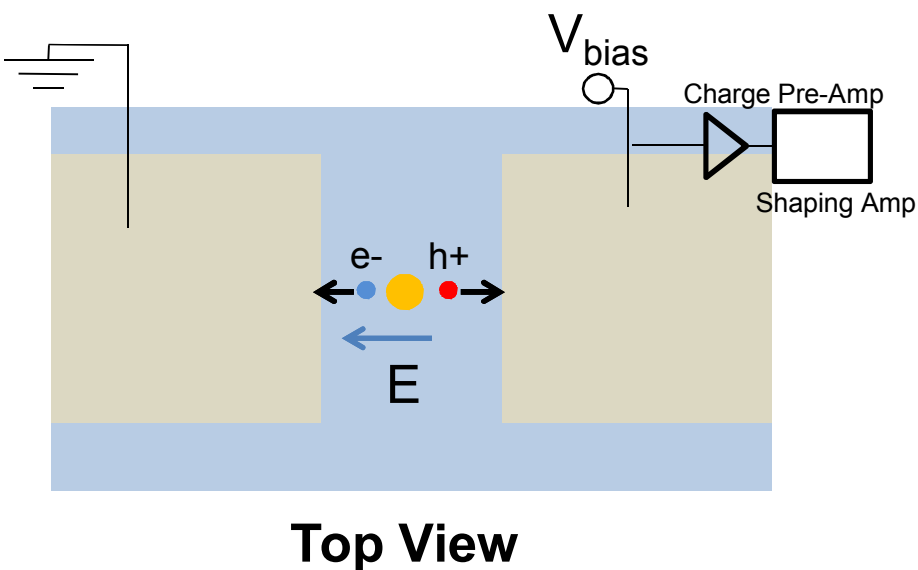
Moving charges in an electrical field will induce a current on the electrodes applying the bias

Charge Collection Efficiency (CCE):

$$CCE = \frac{\text{Charge Collected}}{\text{Charge Deposited}}$$

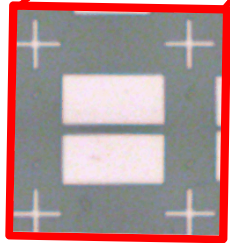
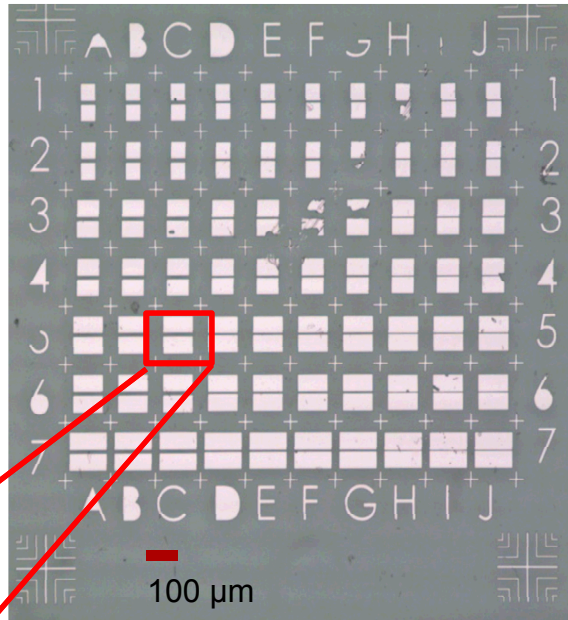
Ion Beam Induced Charge (IBIC):

Ion Beam is rastered across device to measure the Charge Collection Efficiency (CCE) as a function of position



Fabrication/TCAD Modeling

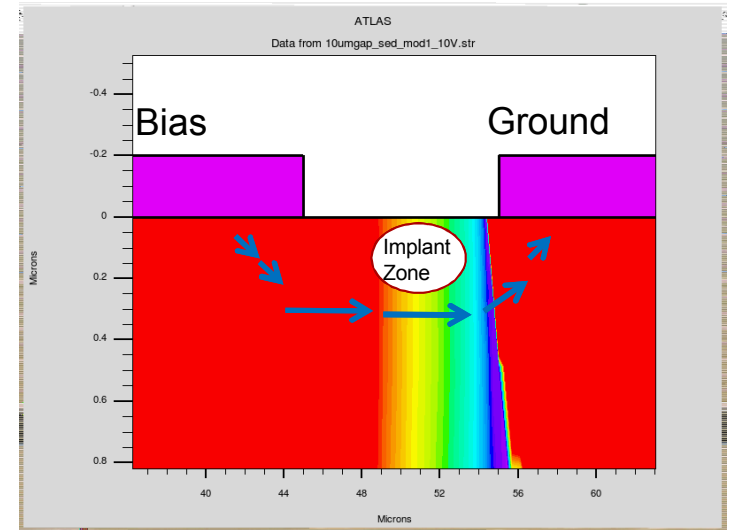
Co-planar
Surface
Electrode
Detector



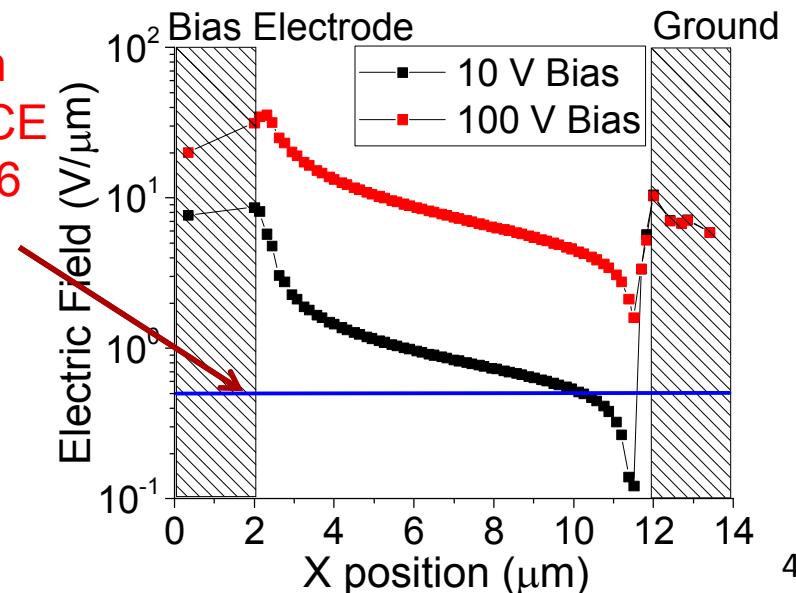
Fabrication

- Electronic grade single crystal diamond (Element 6)
- 200 nm Ti/Pt/Au Electrodes
- Varied width and gap spacing
 - 50-125 μm width
 - 2 – 10 μm gaps

(TCAD) Electric field simulation

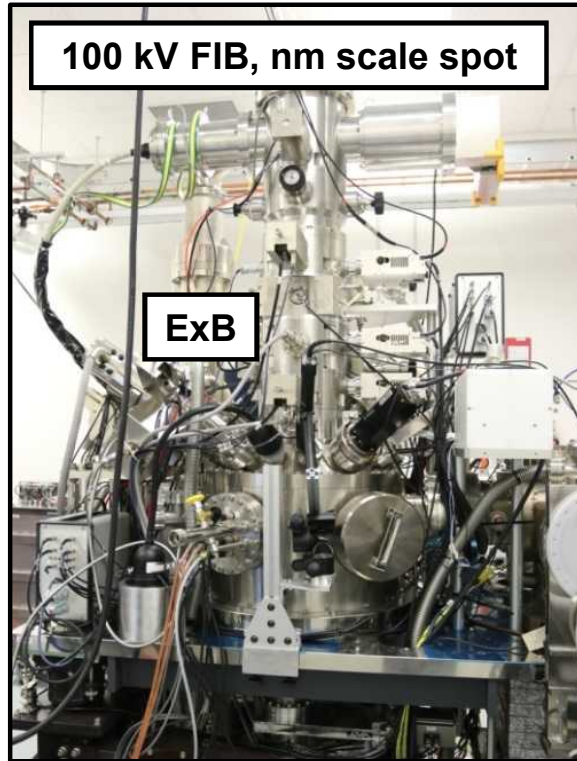


Confirm
95% CCE
From E6



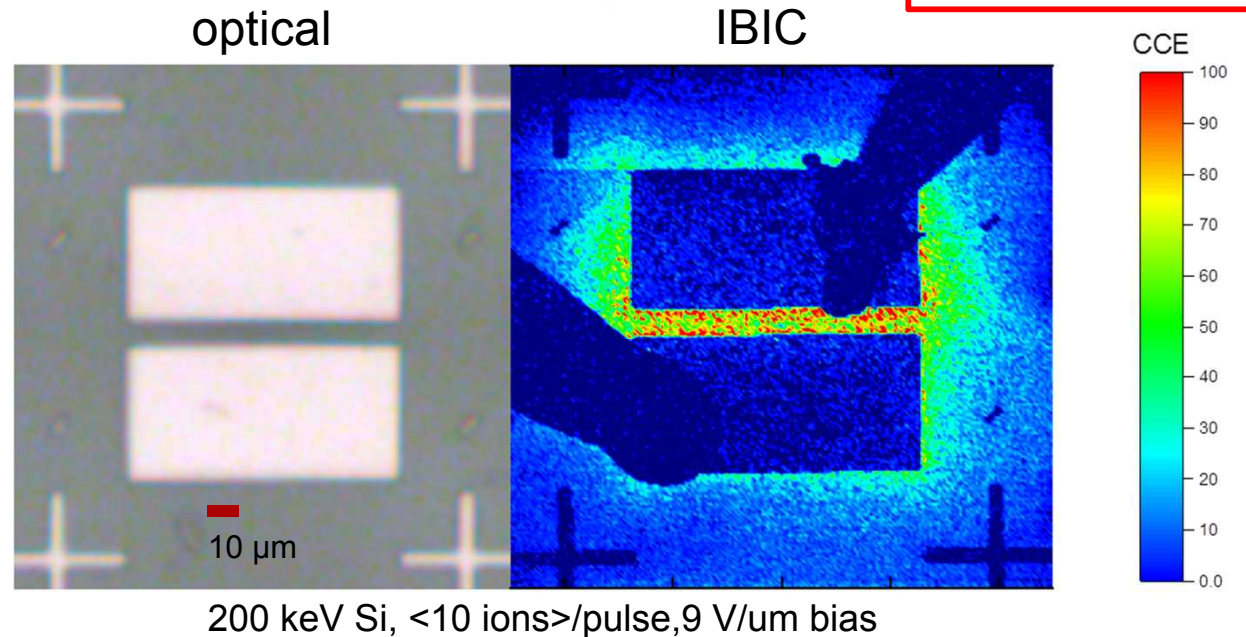
Detector Characterization

SNL NanoImplanter (nl)



- Direct write lithography platform
→ nm targeting accuracy

Ion Beam Induced Current (IBIC)



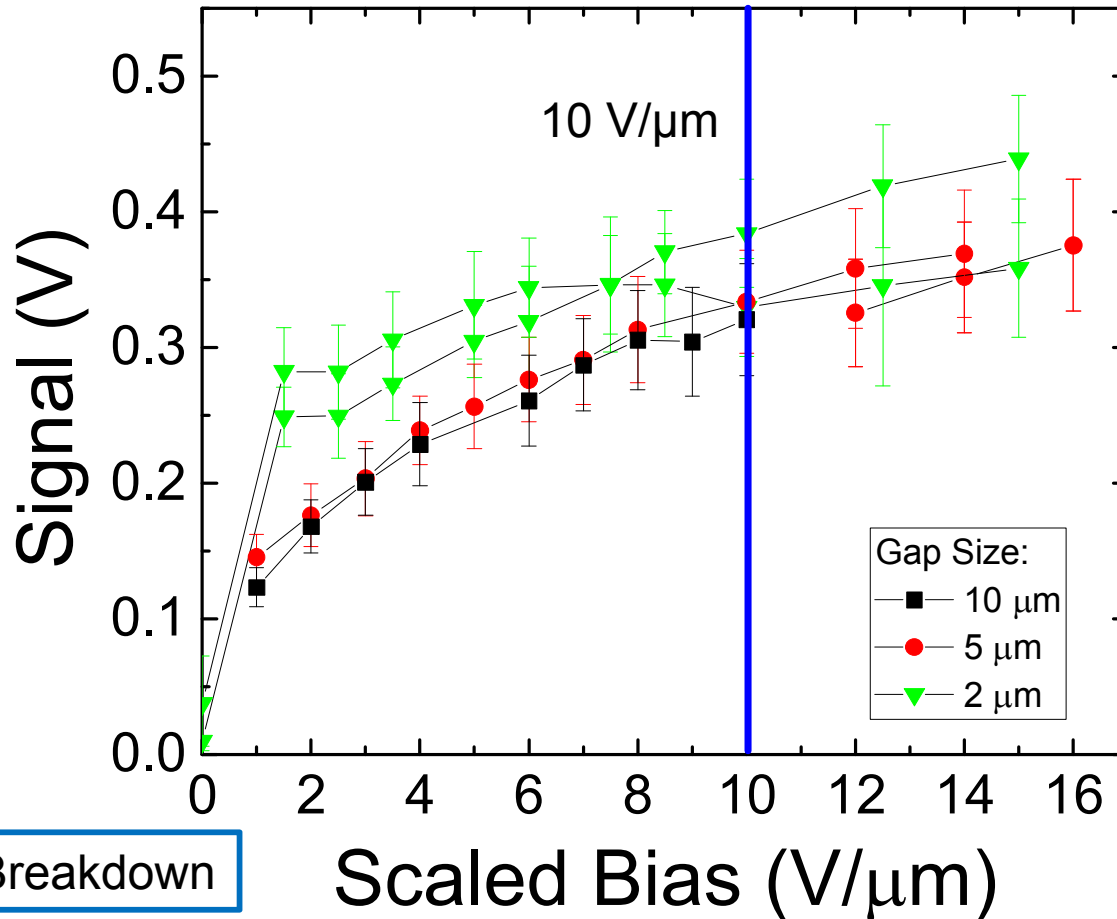
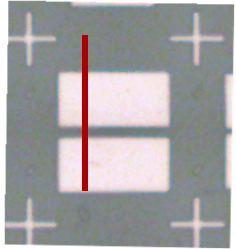
- Good detection in the fielded gap (drift)
- Fair detection in the periphery (diffusion)

IBIC/Detection Demonstrated for low energy heavy ions

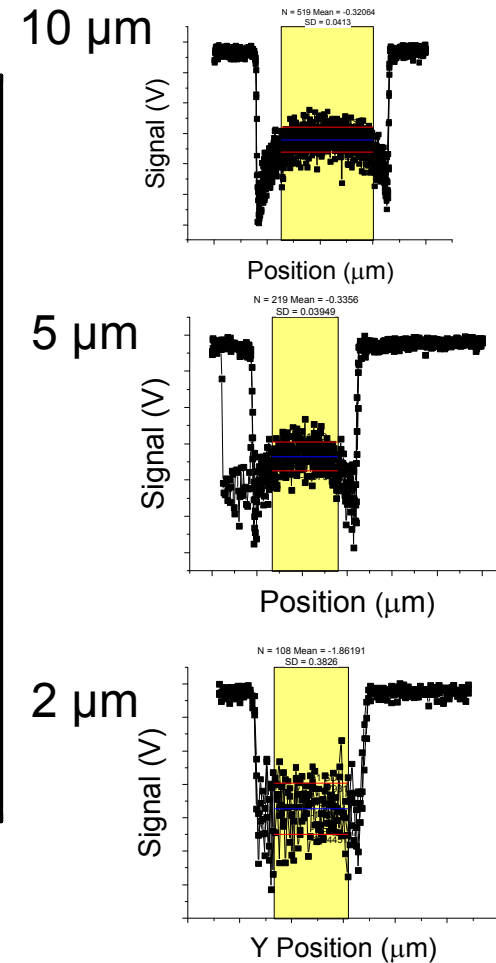
Detector Operation I

$\langle 100 \rangle$ ions/pulse = 100 $\pm$ 10 ions/pulse

Y line cuts



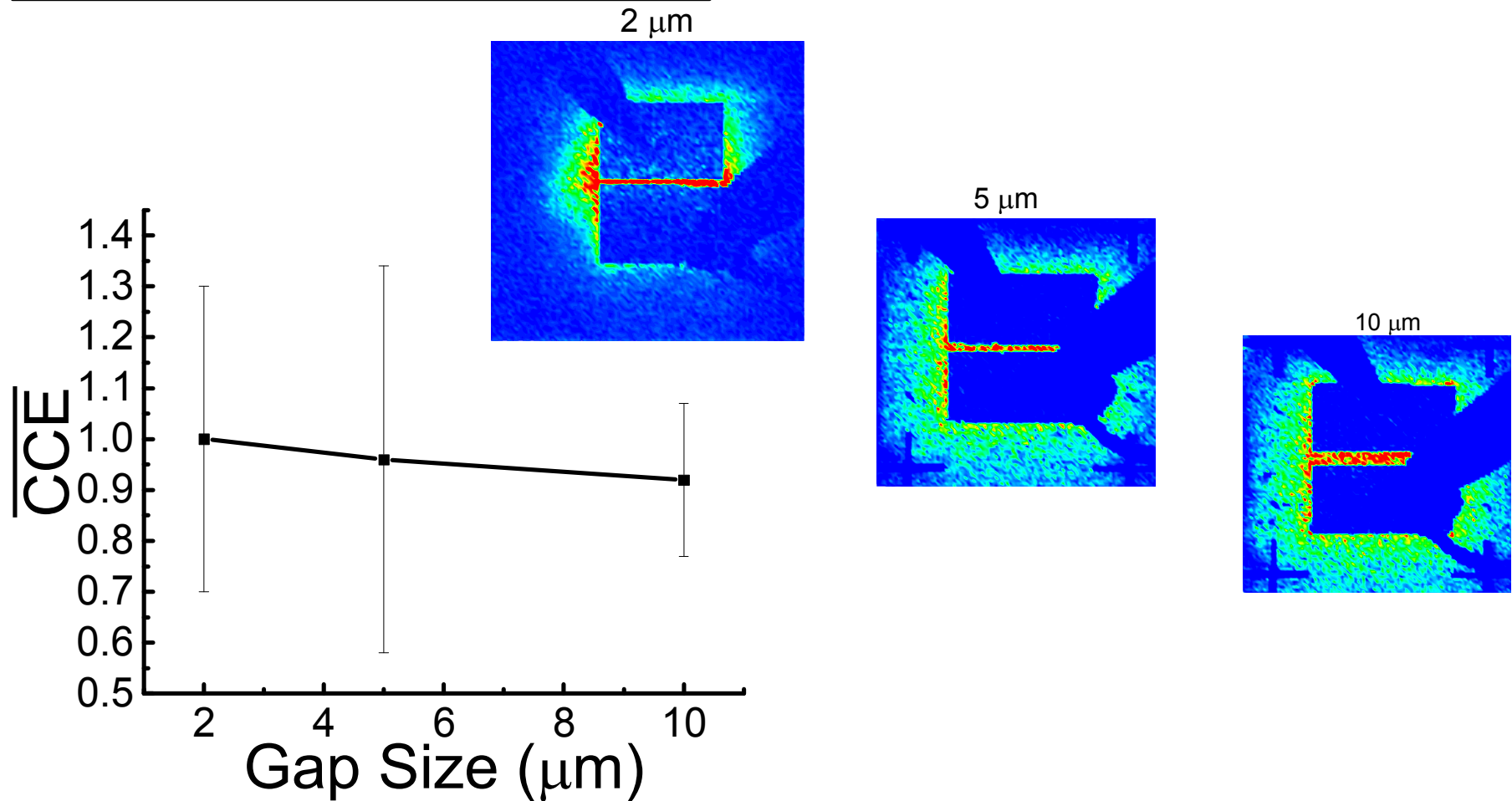
10^3 V/μm: Breakdown



Smaller Gap has a more uniform response and requires less bias for saturation

Detector Operation II

$\langle 10 \rangle$ ions/pulse = 10 ± 3 ions/pulse

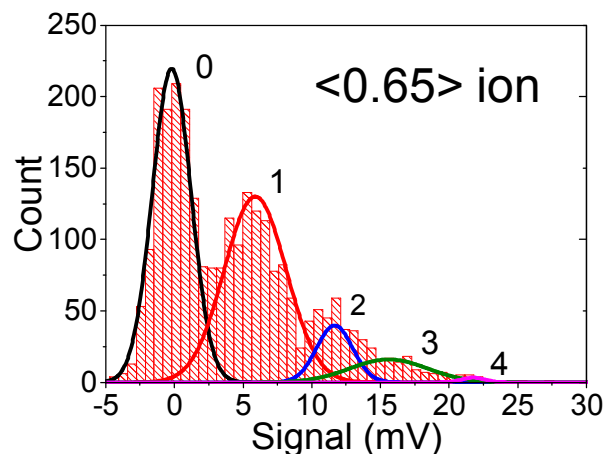
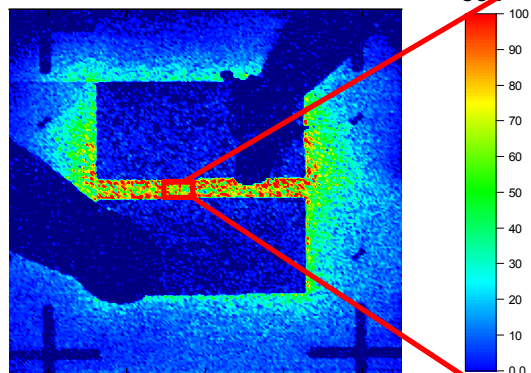


Smaller gap size improves detector performance

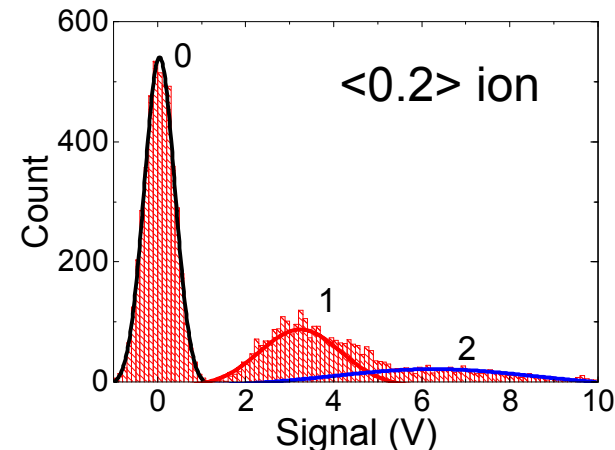
Single Ion Detection

Quantized Detection $\longrightarrow$ Single Ion Counting

IBIC Map

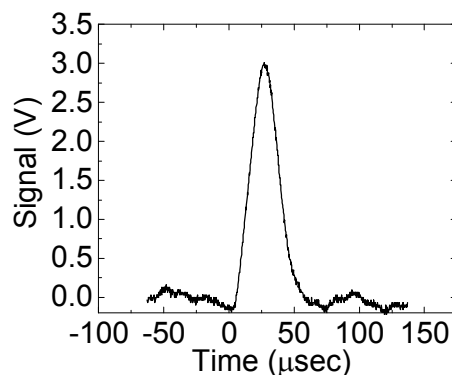
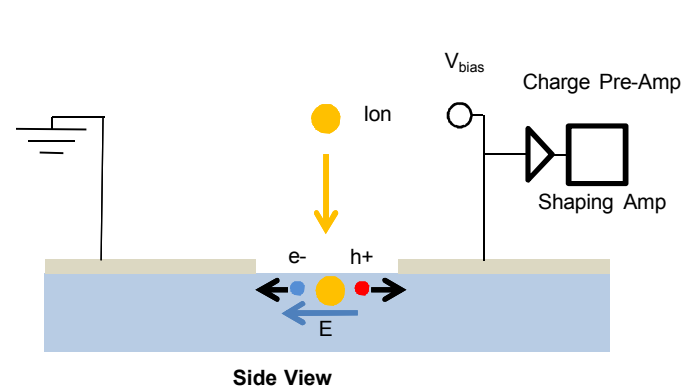


SNR = 1.7



SNR = 3.7

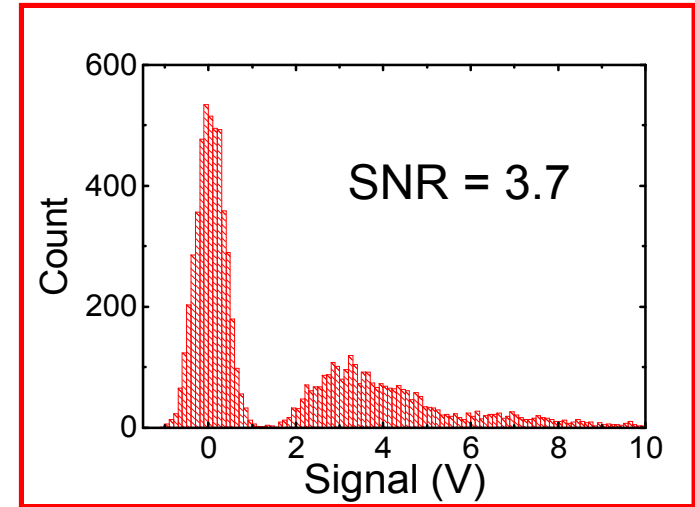
Signal amplitudes match Poisson statistics to 4%



Gate signal for ion beam

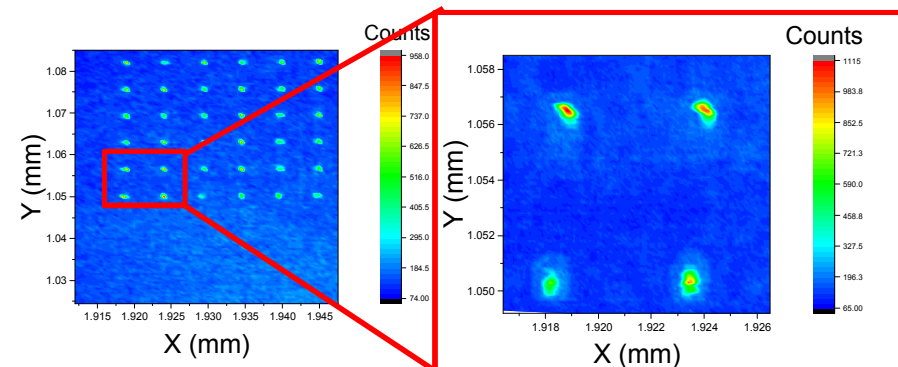
Conclusion/Outlook

- Conclusion:
 - Goal: Counted implantation to minimize Poisson statistics of SiV yield
 - Status: In-situ single ion detection is demonstrated in diamond



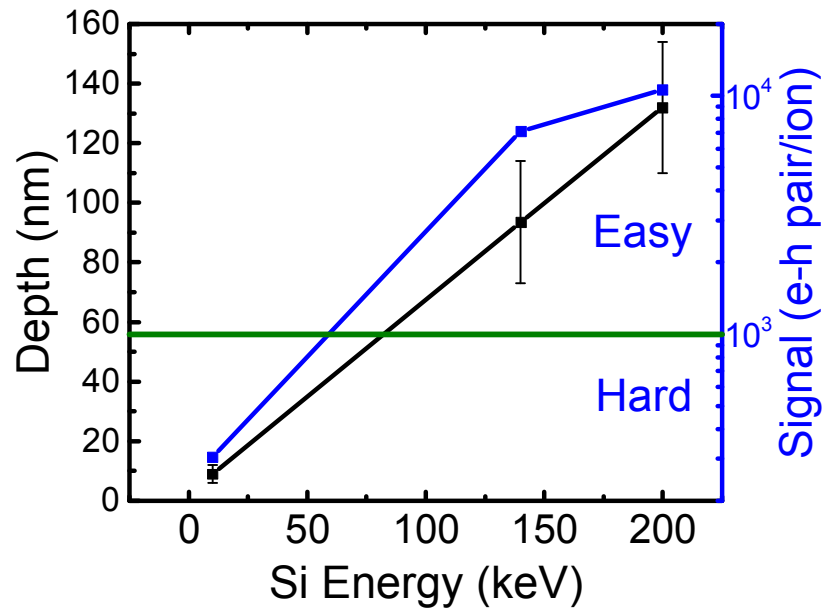
- Follow on work:
 - Measure the yield of a counted implantation.
 - We are in the process of setting up the measurements for yield – PL and g2

738 nm photoluminescence (PL)
of timed SiV

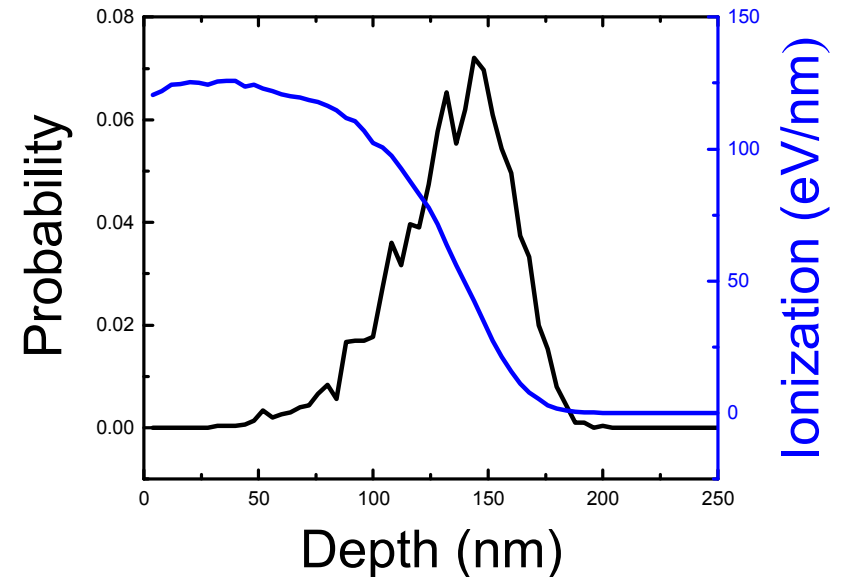


Monte Carlo Simulation (SRIM)

Si implantation

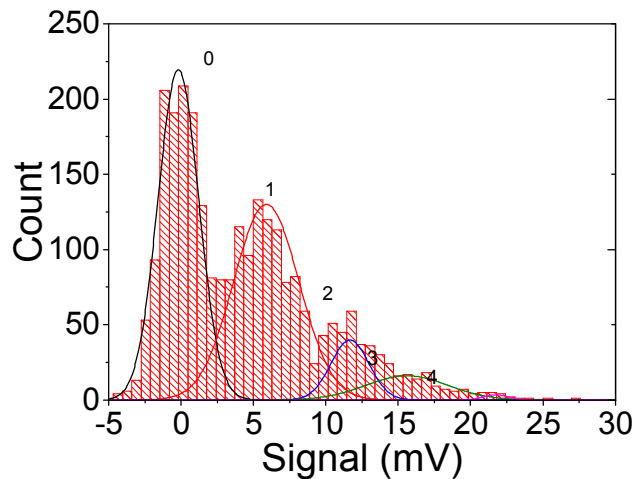


200 keV Si implantation

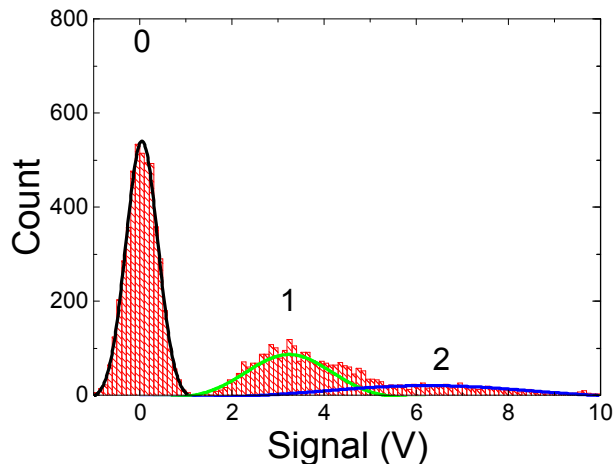


- 200 keV Si into diamond
 - 132 $\pm$ 22 nm depth
 - 10^4 e/h pairs deposited in 75 nm depth

Poisson Statistics of Detection



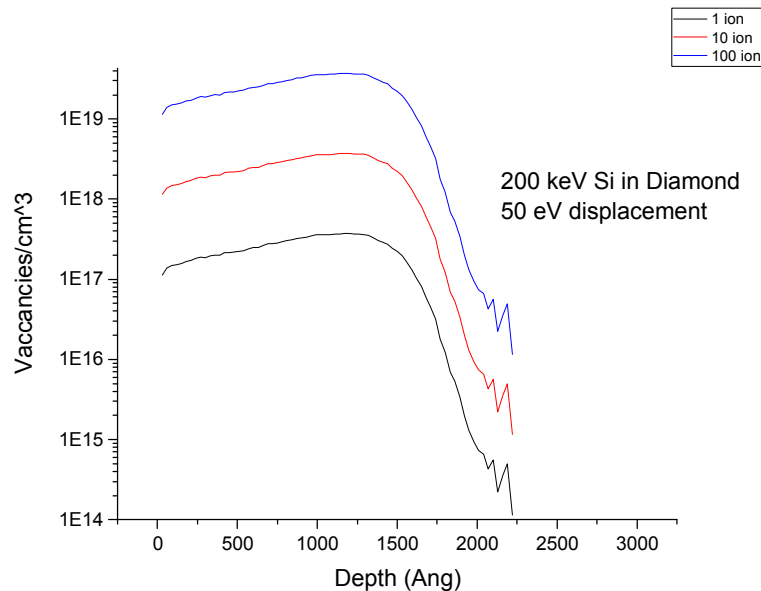
	Experiment	$\langle 0.65 \rangle$
A_0	0.537	.522
A_1	0.319	.339
A_2	.099	.11
A_3	.039	.02
A_4	.007	.009



	Experiment	$\langle 0.2 \rangle$
A_0	.816	.819
A_1	.141	.164
A_2	.052	.016

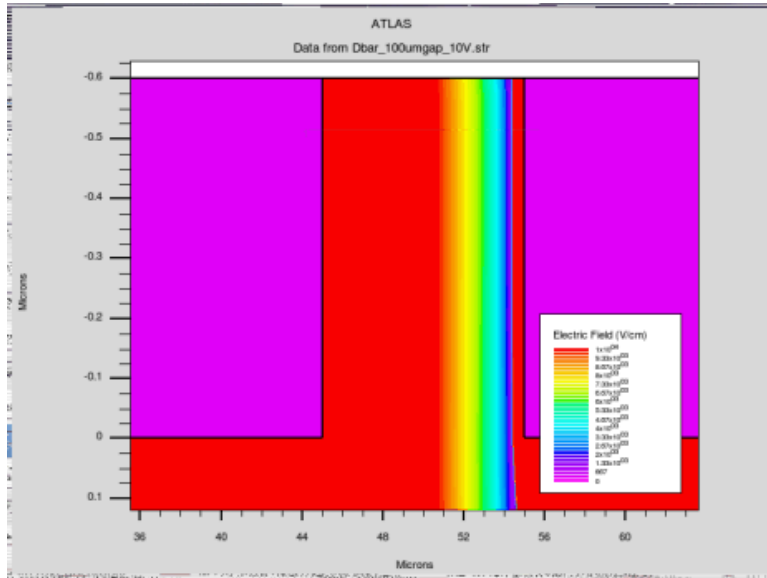
Remaining Detector Questions

- Linearity of response
 - CCE seems to drop off above 10 ions/pulse...



Need to generate a plot of CCE versus Dose for existing data.

How to improve



Paulos stuff with corrugated thing

